



Inventor: Kie Y. Ahn et al.  
Title: A Dielectric Layer Forming Method and Devices Formed Therewith  
Assignee: Micron Technology, Inc.  
Docket No. MI22-1534

**INFORMATION DISCLOSURE STATEMENT**

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56.

Copies of documents listed on the Form PTO-1449 are enclosed.

No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 26 Sep 2003

Attorney: James E. Lake  
James E. Lake  
Reg. No.: 44,854

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Form PTO-1449 O I P E SEP 26 2003 LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1534		SERIAL NO. 09/881,408	
				APPLICANT Kie Y. Ahn, et al					
				FILING DATE June 13, 2001				GROUP 2814	
U.S. PATENT DOCUMENTS									
*Examiner Initial		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate	
	AA	6,544,875	04/2003	Wilk					
	AB	6,573,197	06/2003	Callegari					
	AC	2001/0021589	09/2001	Wilk					
	AD	2002/0048910	04/2002	Taylor et al					
	AE	2003/0027360	02/2003	Hsu					
	AF	2002/0094643	07/2002	Solomon et al					
	AG	2002/0100946	08/2002	Muller et al					
	AH								
	AI								
	AJ								
	AK								
	AL								
FOREIGN PATENT DOCUMENTS									
		Document Number	Date	Country		Class	Subclass	Translation	
	AM							Yes	No
	AN								
	AO								
	AP								
	AO								
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)									
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